

# Electronic Information Disclosure Statement



## High-Power Pulsed Magnetron Sputtering

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TC 1700

Application:



10/065277

Confirmation: 5690

Applicant(s): Roman Chistyakov

Docket Number: ZON-001

Group Art Unit: 1753

Examiner: Unassigned

search string: ( 5015493 or 6296742 or 6413382 or 6436251 or 5875207 or 4953174 or 6296742 or 4965248 ).pn.

### US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Citation No.	Patent Number	Date	Bar Code	Patentee	Class	Subclass
<i>pn</i>	P01	5015493	1991-05-14		Gruen	427	38
<i>pn</i>	P02	6296742	2001-10-02		Kouznetsov	204	192.12
<i>pn</i>	P03	6413382	2002-07-02		Wang et al.	204	192.12
<i>pn</i>	P04	6436251	2002-08-20		Gopalraja et al.	204	298.12
<i>pn</i>	P05	5875207	1999-02-23		Osmanow	372	86
<i>pn</i>	P06	4953174	1990-08-28		Eldridge et al.	372	87
<i>pn</i>	P07	6296742	2001-10-02		Kouznetsov	204	192.12
<i>pn</i>	P08	4965248	1990-10-23		Poppe et al.	505	1



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**Signature**

Examiner Name	Date
<i>Robert M. Gould</i>	1-7-04

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Substitute for form 1449B/PTO		<b>Complete if Known</b>	
		Application Number	10/065,277
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		Filing Date	9/30/2002
		First Named Inventor	Chistyakov
		Group Art Unit	1753
		Examiner Name	McDonald
		Attorney Docket Number	ZON-001
Sheet	2	of	3

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials <sup>1</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T <sup>2</sup>
	C1	BOOTH, ET AL., The Transition From Symmetric To Asymmetric Discharges In Pulsed 13.56 MHz Capacity Coupled Plasmas, J. Appl. Phys., July 15, 1997, Pgs. 552-560, Vol. 82 (2), American Institute of Physics.	
	C2	BUNSHAH, ET AL., Deposition Technologies For Films And Coatings, Materials Science Series, Pgs. 176-183, Noyes Publications, Park Ridge, New Jersey.	
	C3	DAUGHERTY, ET AL., Attachment-Dominated Electron-Beam-Ionized Discharges, Applied Science Letters, May 15, 1976, Vol. 28, No. 10, American Institute of Physics.	
	C4	GOTO, ET AL., Dual Excitation Reactive Ion Etcher for Low Energy Plasma Processing, J. Vac. Sci. Technol. A, Sept./Oct. 1992, Pgs. 3048-3054, Vol. 10, No. 5, American Vacuum Society.	
	C5	KOUZNETSOV, ET AL., A Novel Pulsed Magnetron Sputter Technique Utilizing Very High Target Power Densities, Surface & Coatings Technology, Pgs. 290-293, Elsevier Sciences S.A.	
	C6	LINDQUIST, ET AL., High Selectivity Plasma Etching Of Silicon Dioxide With A Dual Frequency 27/2-MHz Capacitive RF Discharge.	
	C7	MACAK, Reactive Sputter Deposition Process of Al2O3 and Characterization Of A Novel High Plasma Density Pulsed Magnetron Discharge, Linkoping Studies In Science And Technology, 1999, Pgs. 1-2, Sweden.	
	C8	MACAK, ET AL., Ionized Sputter Deposition Using An Extremely High Plasma Density Pulsed Magnetron Discharge, J. Vac. Sci. Technol. A., July/August 2000, Pgs. 1533-37, Vol. 18, No. 4, American Vacuum Society.	

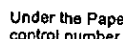
Examiner Signature		Date Considered	1-7-04
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Sheet	3	of	3
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**Complete if Known**

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<b>Examiner Name</b>	McDonald
<b>Attorney Docket Number</b>	ZON-001

**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

Examiner  
Signature

Date \_\_\_\_\_

Considered

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